

L Number	Hits	Search Text	DB	Time stamp
1	1	("6120660").PN.	USPAT;	2003/01/22 11:22
4	3	6120660.URPN.	US-PGPUB	2003/01/22 11:20
5	24	("4764394" "4808546" "4933063" "5032202" "5183775" "5196355" "5289010" "5296272" "5304279" "5305221" "5311028" "5342652" "5380682" "5427638" "5436175" "5525159" "5554249" "5554853" "5580429" "5641707" "5653811" "5661043" "5711812" "5854123").PN.	USPAT	2003/01/22 11:22
6	19	((("4764394" "4808546" "4933063" "5032202" "5183775" "5196355" "5289010" "5296272" "5304279" "5305221" "5311028" "5342652" "5380682" "5427638" "5436175" "5525159" "5554249" "5554853" "5580429" "5641707" "5653811" "5661043" "5711812" "5854123").PN.) and (silicon polysilicon)	USPAT; US-PGPUB	2003/01/22 14:37
9	1	("6120660").PN.	USPAT;	2003/01/22 14:37
-	38983	c23c016\$.ipc.	US-PGPUB	2002/09/06 10:43
-	660865	h01I021\$.ipc.	JPO; DERWENT	2002/05/07 13:21
-	0	118/719.ccls. and (centura with "htf")	JPO; DERWENT	2002/05/07 13:21
-	15	(centura with "htf")	USPAT; US-PGPUB	2003/01/17 11:23
-	160	(holder susceptor chuck) with carbon with silicon	USPAT; US-PGPUB	2003/01/17 11:14
-	120	(holder susceptor chuck) with carbon with silicon	USPAT; US-PGPUB	2003/01/17 11:30
-	3	(holder susceptor chuck) with carbon with polysilicon	EPO; JPO; DERWENT	2003/01/21 10:36
-	4	(holder susceptor chuck) with carbon with polysilicon	EPO; JPO; DERWENT	2003/01/17 11:22
-	39	118/728.ccls. and (carbon with (susceptor holder chuck))	USPAT; US-PGPUB	2003/01/17 11:18
-	89	(holder susceptor chuck) with carbon with (protect\$3 shield\$3)	USPAT; US-PGPUB	2003/01/17 11:24
-	33	(holder susceptor chuck) with carbon with (protect\$3 shield\$3) with (coat\$3 layer\$3 film deposit\$3)	USPAT; US-PGPUB	2003/01/17 11:31
-	15	((holder susceptor chuck) with carbon) same (clean\$3 with gas)	USPAT; US-PGPUB	2003/01/17 11:39
-	24	((holder susceptor chuck) with carbon) same (clean\$3 with gas)	EPO; JPO; DERWENT	2003/01/17 11:40
-	106	((holder susceptor chuck) with polysilicon)	USPAT; US-PGPUB	2003/01/17 11:42
-	45	((holder susceptor chuck) with polysilicon)	USPAT; US-PGPUB	2003/01/17 11:45
-	0	(kataoka.in. sato.in.) same polysilicon	EPO; JPO; DERWENT	2003/01/17 11:57
-	0	(kataoka-takahashi.in. sato-hirosuke.in.) same polysilicon	EPO; JPO; DERWENT	2003/01/17 11:57
-	2	(kataoka-takahashi.in. sato-hirosuke.in.) and polysilicon	EPO; JPO; DERWENT	2003/01/17 11:58
-	5	(toshiba) and (polysilicon same (susceptor chuck holder))	EPO; JPO; DERWENT	2003/01/17 11:58
-	106	((holder susceptor chuck) with polysilicon)	EPO; JPO; DERWENT	2003/01/17 11:59
-	1	6071353.URPN.	USPAT;	2003/01/17 12:04
-	73	(holder susceptor chuck) with carbon with silicon with (coat\$3 deposit\$3 cover\$3)	USPAT; US-PGPUB	2003/01/17 12:20
-	1	(holder susceptor chuck) with carbon with (coat\$3 layer\$3 film) with (gas) with clean\$3	USPAT; US-PGPUB	2003/01/17 12:37
-	3	(holder susceptor chuck) with carbon with (coat\$3 layer\$3 film) with (gas) with clean\$3	USPAT; US-PGPUB	2003/01/17 12:39
-			EPO; JPO; DERWENT	2003/01/17 12:39

-	407	(holder susceptor chuck) with carbon with (coat\$3 layer\$3 film)	EPO; JPO; DERWENT	2003/01/17 12:59
-	427	(holder susceptor chuck) with carbon with (coat\$3 layer\$3 film)	USPAT; US-PGPUB	2003/01/17 12:40
-	284	(holder susceptor chuck support) with carbon with (coat\$3 layer\$3 film) with (protect\$3 strength strong)	USPAT; US-PGPUB	2003/01/17 13:02
-	174	(holder susceptor chuck support) with carbon with (coat\$3 layer\$3 film) with (protect\$3 strength strong)	EPO; JPO; DERWENT	2003/01/17 13:03
-	135	(holder susceptor chuck support) with carbon with silicon with carbide	EPO; JPO; DERWENT	2003/01/21 10:37
-	135	(holder susceptor chuck support) with carbon with silicon with carbide	EPO; JPO; DERWENT	2003/01/21 11:29
-	399	(holder susceptor chuck support) with carbon with silicon with carbide	USPAT; US-PGPUB	2003/01/21 11:26
-	19	(holder susceptor chuck support) with carbon with silicon with poly\$1crystalline	EPO; JPO; DERWENT	2003/01/21 11:02
-	4376	(holder susceptor chuck support) with carbon with (coat\$3 deposit\$3 film)	USPAT; US-PGPUB	2003/01/21 11:28
-	1558	(holder susceptor chuck support) with carbon with (coat\$3 deposit\$3 film)	EPO; JPO; DERWENT	2003/01/21 11:28
-	144	(susceptor) with carbon with (coat\$3 deposit\$3 film)	EPO; JPO; DERWENT	2003/01/21 12:30
-	119	((susceptor) with carbon with (coat\$3 deposit\$3 film)) not ((holder susceptor chuck support) with carbon with silicon with carbide)	EPO; JPO; DERWENT	2003/01/21 11:29
-	172	(susceptor) with carbon with (coat\$3 deposit\$3 film)	USPAT; US-PGPUB	2003/01/21 12:31
-	1	(susceptor) with carbon with (coat\$3 deposit\$3 film) with (rate speed) with (heat\$3 temperature)	USPAT; US-PGPUB	2003/01/21 12:31
-	1821	118/\$.ccls. and ((control\$3 computer) with (pressur\$3 vacuum) with gas)	USPAT; US-PGPUB	2003/01/21 14:07
-	804	c23c016\$.ipc. and ((control\$3 computer) with (pressur\$3 vacuum) with gas)	EPO; JPO; DERWENT	2003/01/21 14:08
-	67	118/\$.ccls. and ((control\$3 computer) with (pressur\$3 vacuum) with gas with coupl\$3)	USPAT; US-PGPUB	2003/01/21 15:29
-	1104	(118/728).CCLS.	USPAT; US-PGPUB	2003/01/21 15:29
-	124	((118/728).CCLS.) and (polysilicon)	USPAT; US-PGPUB	2003/01/21 15:29
-	1	6071353.URPN.	USPAT	2003/01/21 15:35
-	5	("4867841" "5565038" "5849092" "5868852" "5926743").PN.	USPAT	2003/01/21 15:36